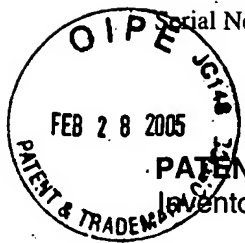


IFW



Serial No. 10/674448

IN THE UNITED STATES  
PATENT AND TRADEMARK OFFICE

PATENT APPLICATION

Inventor(s): Marc Scott Hodes Alan Michael Lyons  
Paul Robert Kolodner Mary Louise Mandich  
Thomas Nikita Krupenkin Joseph Ashley Taylor

Case: 3-10-15-19-13-6

Serial No.: 10/674448

Filing Date: September 30, 2003

Examiner: Group Art Unit:

Title: Reversible Transitions On Dynamically Tunable Nanostructured Or  
Microstructured Surfaces

COMMISSIONER FOR PATENTS  
P.O. BOX 1450  
ALEXANDRIA, VA 22313-1450  
SIR:

**INFORMATION DISCLOSURE STATEMENT**  
**CERTIFICATION UNDER 37 CFR 1.97(c)(1)**

In accordance with 37 CFR 1.97(c)(1), the enclosed Information Disclosure Statement, with attached reference(s), is submitted for consideration in the above-identified application.

I certify that each item of information contained in the Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement. Copies of the listed documents are enclosed together with the search report that listed these documents.

**NO FEE IS REQUIRED**

In the event of any non-payment or improper payment of a required fee, the Commissioner is authorized to charge or to credit **Lucent Technologies Deposit Account No. 12-2325** as required to correct the error.

Respectfully,

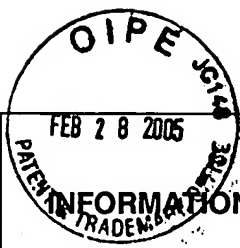
Donald P. Dinella, Attorney  
Reg. No. 39961  
908-582-8582

Date: 02/21/05

Docket Administrator (Room 3J-219)  
Lucent Technologies Inc.  
101 Crawfords Corner Road  
Holmdel, NJ 07733-3030

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, PO Box 1450, Alexandria, VA 22313-1450, on February 25, 2005.

Rose E. Ewald



<b>INFORMATION DISCLOSURE STATEMENT</b>	Case Name.	M.S. Hodes 3-10-15-19-13-6
	Serial No.	10/674448
	Applicant:	M.S. Hodes, et al.
	Filing Date:	September 30, 2003
	Group:	

### U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date
AA	2003/0148401	8/7/2003	Anoop Agrawal, et al	435/7.9	435/287.2	11/8/2002

### FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation
AB	DE 197 05 910	6/18/1998	EPC	B 01 L 3/00	H 01 L 49/00	No
AC	WO 03/071335	8/28/2003	PCT	G02B 27/00		Yes
AD	WO 03/083447	10/9/2003	PCT	G01N 13/02	B01L 3/00	Yes
AE	0 290 125	11/9/1988	EPC	G02B 1/10		Yes
AF	WO 03/056330	7/10/2003	PCT	G01N 33/50		Yes

### OTHER (including Author, Title, Date, Pertinent Pages, etc.)

AG	E. W. Becker, et al, "Fabrication of microstructures with high aspect ratios and great structural heights by synchrotron radiation lithography, galvanofarming, and plastic moulding (LIGA process)", <i>Micro-electronic Engineering, Elsevier Publishers BV., Amsterdam, NL</i> , vol. 4, no. 1, (5/1/1986), pp. 35-56.
AH	European Search Report

\*\*\*References listed beyond AZ would list as AA-1, AB-2, AC-3 thru AZ-26.

\*\*\*Note First Page ONLY Header/Footer. Subsequent pages must ONLY have page # layout as header

EXAMINER	DATE CONSIDERED
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\***Examiner:** Initial if reference considered, whether or not citation is in conformance with MPEP 609: Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant